

**BEST AVAILABLE COPY****Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1-31 (Canceled).

32. (Previously Presented) A method of manufacturing many different inductive plasma processors of the same type, each of the processors including a plasma excitation coil having plural electrically connected windings, each of the windings having a pair of excitation terminals, the windings of the coil of each processor being adapted to be driven by an excitation source arrangement so that different currents simultaneously flow through the pair of excitation terminals of each winding, the plural windings of each coil of each processor being arranged so an exterior winding of the coil is about an interior winding of the coil, the exterior winding and the interior winding being about an axis of the coil, the different processors of the same type having differing electric field and plasma density distributions from processor to processor, the method comprising for each of the inductive plasma processors:

moving the position of the exterior and interior windings relative to each other and the axis so the plasma density incident on a workpiece in a chamber of the processor has a predetermined desired relationship until tests conducted on each processor indicate optimum uniform plasma distribution is achieved in each processor.

33. (Previously Presented) The method of claim 32 wherein the different processors of the same type have differing azimuthal electric field distributions, and wherein the movement of the exterior and interior windings relative to each other